



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

2 Application Serial No. .... 09/298,160  
3 Filing Date ..... April 22, 1999  
4 Inventor ..... Dan G. Custer et al.  
5 Assignee ..... Micron Technology, Inc.  
6 Group Art Unit ..... 1746  
7 Examiner ..... A. Olsen  
8 Attorney's Docket No. .... MI22-1172  
9 Title: Polishing Systems, Methods of Polishing Substrates, and Methods of Preparing  
10 Liquids for Semiconductor Fabrication Processes  
11  
12  
13

**RESPONSE TO 09/27/2000 OFFICE ACTION**

14 To: Assistant Commissioner for Patents  
15 Washington, D.C. 20231

16 From: Bernard Berman (Tel. 509-624-4276; Fax 509-838-3424)  
17 Wells, St. John, Roberts, Gregory & Matkin P.S.  
18 601 W. First Avenue, Suite 1300  
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20 Sir:

21 Responsive to the Office Action dated September 27, 2000,  
22 applicant requests reconsideration of the above referenced application in  
23 view of the amendments and remarks that follow [unless otherwise  
indicated, deletions are bracketed, additions are underlined]:

10/10  
11-8-00  
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